

## EAST Search History (Interference)

| Ref # | Hits | Search Query   | DBs            | Default Operator | Plurals | Time Stamp       |
|-------|------|--|----------------|------------------|---------|------------------|
| L9    | 4    | ((wafer or semiconductor or substrate) nozzle near7 mix near7 gas near7 liquid).clm.                                       | US-PGPUB; UPAD | AND              | ON      | 2011/06/29 15:49 |
| L10   | 6    | ((wafer or semiconductor or substrate) nozzle mix near7 gas near7 liquid).clm.   | US-PGPUB; UPAD | AND              | ON      | 2011/06/29 15:50 |
| L11   | 62   | ((wafer or semiconductor or substrate) nozzle mix\$3 near7 gas near7 liquid).clm.  | US-PGPUB; UPAD | AND              | ON      | 2011/06/29 15:50 |
| L12   | 30   | ((wafer or semiconductor or substrate) nozzle mix\$3 near7 gas near7 liquid step\$3).clm.                                  | US-PGPUB; UPAD | AND              | ON      | 2011/06/29 15:52 |
| L13   | 1    | ((wafer or semiconductor or substrate) nozzle mix\$3 near7 gas near7 liquid step\$3 near8 (port or passage)).clm.          | US-PGPUB; UPAD | AND              | ON      | 2011/06/29 15:52 |
| L14   | 11   | ((wafer or semiconductor or substrate) nozzle mix\$3 near7 gas near7 liquid (port or passage) near5 (gas and liquid)).clm. | US-PGPUB; UPAD | AND              | ON      | 2011/06/29 15:53 |